


**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Shiva Prakash  
Title: Atomic Force Microscopy Measurements Of Contact Resistance And Current-Dependent Stiction  
Serial No. New – Divisional of Serial No. 10/202,439 filed 07/23/2002  
Filing Date: Herewith  
Prior Art Unit: 2856  
Prior Examiner: R. Raevis  
Atty Docket: 061450/0304607 (FID-101-D3)

MAIL STOP: Patent Applications  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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Date of Deposit: July 3, 2003

I hereby certify that this correspondence and the documents referred to as attached hereto are being deposited with the United States Postal Service on the above date in an envelope marked as "Express Mail Post Office to Addressee," addressed to MAIL STOP Patent Applications, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

  
Kathleen M. Smith

**INFORMATION DISCLOSURE STATEMENT**

Applicant submits herewith patents, publications or other information of which Applicant is aware which are believed to be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR 1.56.

The filing of this information disclosure statement shall not be construed as a representation that a search has been made (37 CFR 1.97(g)), nor as an admission that the information cited is, or is considered to be, material to patentability, nor an admission that no other material information exists. The filing of this information disclosure statement shall not be construed as an admission against interest in any manner. Notice of January 9, 1992, 1135 O.G. 13-25, at 25.

The references cited herein were cited in the parent application Serial No. 10/202,439 filed July 23, 2002, and therefore copies are not included.

Respectfully submitted  
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**EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.